


CFW

AMENDMENT TRANSMITTAL LETTER (Large Entity)			Docket No. SEC.910		
Applicant(s): Kyoung-Hwan CHIN et al.					
Serial No. 09/988,302	Filing Date 19 November 2001	Examiner Gentle WINTER	Group Art Unit 1746		
Invention: CLEANING APPARATUS OF A HIGH DENSITY PLASMA CHEMICAL VAPOR DEPOSITION CHAMBER AND CLEANING METHOD THEREOF					
<u>TO THE COMMISSIONER FOR PATENTS:</u>					
Transmitted herewith is an amendment in the above-identified application. The fee has been calculated and is transmitted as shown below.					
CLAIMS AS AMENDED					
	CLAIMS REMAINING AFTER AMENDMENT	HIGHEST # PREV. PAID FOR	NUMBER EXTRA CLAIMS PRESENT	RATE	ADDITIONAL FEE
TOTAL CLAIMS	9 -	20 =	0 x	\$18.00	\$0.00
INDEP. CLAIMS	2 -	3 =	0 x	\$86.00	\$0.00
Multiple Dependent Claims (check if applicable) <input type="checkbox"/>					\$0.00
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT					\$0.00
<div style="display: flex; justify-content: space-between;"><div><input checked="" type="checkbox"/> No additional fee is required for amendment. <input type="checkbox"/> Please charge Deposit Account No. _____ in the amount of _____ <input type="checkbox"/> A check in the amount of _____ to cover the filing fee is enclosed. <input type="checkbox"/> The Director is hereby authorized to charge payment of the following fees associated with this communication or credit any overpayment to Deposit Account No. <div style="margin-left: 20px;"><input type="checkbox"/> Any additional filing fees required under 37 C.F.R. 1.16. <input type="checkbox"/> Any patent application processing fees under 37 CFR 1.17.</div></div><div style="text-align: right;">Dated: 24 May 2004</div></div>					
<div style="display: flex; justify-content: space-between;"><div style="width: 60%;"><div style="text-align: center;"> _____ <small>Signature</small></div><div>KENNETH D. SPRINGER REG. NO.: 39,843 VOLENTINE FRANCOS, PLLC 12200 SUNRISE VALLEY DRIVE, SUITE 150 RESTON, VA 20191 TEL. NO.: (703) 715-0870</div></div><div style="width: 35%; border: 1px solid black; padding: 5px;"><div style="font-size: small;">I certify that this document and fee is being deposited on _____ with the U.S. Postal Service as first class mail under 37 C.F.R. 1.8 and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.</div><div style="border-top: 1px solid black; height: 20px; margin-top: 10px;"></div><div style="border-top: 1px solid black; height: 20px; margin-top: 10px;"></div></div></div>					
<div style="display: flex; justify-content: space-between;"><div>CC:</div><div style="width: 60%;"><div style="text-align: center; font-size: small;">Signature of Person Mailing Correspondence</div><div style="border-top: 1px solid black; height: 20px; margin-top: 5px;"></div><div style="text-align: center; font-size: small;">Typed or Printed Name of Person Mailing Correspondence</div></div></div>					



Serial No. 09/988,302

SEC.910

Amendment dated 24 May 2004

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:

Kyoung-Hwan CHIN et al.

Group Art Unit: 1746

Serial No.: 09/988,302

Examiner: Gentle WINTER

Filed: 19 November 2001

CLEANING APPARATUS OF A
HIGH DENSITY PLASMA
CHEMICAL VAPOR DEPOSITION
CHAMBER AND CLEANING
METHOD THEREOF

AMENDMENT UNDER 35 C.F.R. 1.111

U.S. Patent and Trademark Office
2011 South Clark Place
Customer Window, Mail Stop Non-Fee Amendment
Crystal Plaza Two, Lobby, Room 1B03
Arlington, VA 22202

Sir:

In response to the Office Action dated 25 February 2004, the period for response to which extends through 25 May 2004, please amend the above-identified patent application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks begin on page 6 of this paper.